

Listing of Claims:

1. (Currently Amended) An electrostatic attraction type liquid ejection apparatus comprising:

an opposing electrode;

5 a liquid ejection head having: ~~a nozzle~~ with (i) plural nozzles arranged on a same plane facing a same direction so as to face the opposing electrode, each of the nozzles having an inner diameter of at most 15 μm , (ii) a flexible base layer, (iii) an insulating layer formed over an entire surface of the flexible base layer, (iv) a flow channel layer which has a solution chamber and a supply channel for each of the nozzles, and which is positioned over the insulating layer for forming the supply channels of a solution, (v) a nozzle plate which has the nozzles and which is formed over the flow channel layer, and (vi) an ejection electrode which is arranged at an entire boundary
10 between the flow channel layer and the nozzle plate;

15 an ejection voltage supply to apply an ejection voltage to
[[a]] the solution inside the ~~nozzle~~ nozzles via the ejection electrode so as to charge the solution in the solution chambers,
the ejection voltage supply including ~~an electrode~~ the ejection
20 electrode which contacts with the solution to charge the solution;

a convex meniscus generator: (i) which has a piezoelectric transducer and a drive voltage supply for applying a drive voltage to the piezoelectric transducer to deform the piezoelectric transducer, and (ii) which is provided for each of the nozzles, to cause the solution inside ~~the nozzle~~ each of the nozzles to rise ~~from the nozzle therefrom~~ in a convex shape; and

an operation controller to control application of [[a]] the drive voltage to drive ~~the~~ each convex meniscus generator and application of the ejection voltage by the ejection voltage supply so that the drive voltage to ~~the~~ each convex meniscus generator is applied in a timing corresponding to the application of a pulse voltage as the ejection voltage by the ejection voltage supply;

wherein the operation controller controls the ejection voltage supply to apply a voltage ~~having~~ which has a reversed polarity to the ejection voltage to be applied by the ejection electrode, and which is applied to the solution inside ~~the nozzle~~ each of the nozzles via the ejection electrode just before or just after the ejection voltage is applied to the solution inside ~~the nozzle~~ each of the nozzles.

Claim 2 (Canceled).

3. (Currently Amended) The electrostatic attraction type liquid ejection apparatus of claim 1, wherein the operation controller applies the drive voltage to ~~the~~ each convex meniscus generator in advance, and also in the timing corresponding to the application of the pulse voltage as the ejection voltage by the ejection voltage supply.

Claims 4-8 (Canceled).

9. (Currently Amended) The electrostatic attraction type liquid ejection apparatus of claim 1, wherein the inner diameter of ~~the nozzle~~ each of the nozzles is between 0.2 μm and 8 μm .

10. (Currently Amended) The electrostatic attraction type liquid ejection apparatus of claim 9, wherein the inner diameter of ~~the nozzle~~ each of the nozzles is between 0.2 μm and 4 μm .

Claim 11 (Canceled).

12. (Currently Amended) The electrostatic attraction type liquid ejection apparatus of claim [[4]] 1, ~~further comprising an~~ wherein the opposing electrode ~~having~~ has an opposing surface which faces top portions of the plurality of nozzles and which supports a substrate.

13. (Previously Presented) The electrostatic attraction type liquid ejection apparatus of claim 12, wherein the opposing electrode is provided in common for the plurality of nozzles so as to face the top portions of the plurality of nozzles.

14. (Currently Amended) The electrostatic attraction type liquid ejection apparatus of claim [[4]] 1, wherein the ejection voltage supply is provided in common for the plurality of nozzles so as to apply the ejection voltage to the solution inside each
5 of the plurality of nozzles.

15. (Previously Presented) The electrostatic attraction type liquid ejection apparatus of claim 1, wherein the liquid ejection apparatus is provided in an ink jet printer.

16. (Currently Amended) The electrostatic attraction type liquid ejection apparatus of claim 1, wherein the inner diameter of ~~the nozzle~~ each of the nozzles is uniform through a length thereof ~~of the nozzle~~.

17. (Currently Amended) The electrostatic attraction type liquid ejection apparatus of claim 1, wherein the inner diameter of ~~the nozzle~~ each of the nozzles is tapered.

18. (Currently Amended) The electrostatic attraction type liquid ejection apparatus of claim 17, wherein the inner diameter of ~~the nozzle~~ each of the nozzles is larger at a solution-chamber side ~~of the nozzle~~ and gradually decreases toward an ejection-
5 opening side ~~of the nozzle~~.

19. (Currently Amended) The electrostatic attraction type liquid ejection apparatus of claim 1, wherein ~~the nozzle~~ each of the nozzles has a substantially conical shape.

20. (Currently Amended) The electrostatic attraction type liquid ejection apparatus of claim 1, wherein ~~the nozzle~~ each of the nozzles has a height of approximately 100 μm .